

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of

Ji-soo KIM et al.

Serial No.: [NEW]

Attn: Applications Branch

Filed: 30 September 2003

For: METHOD OF DETERMINING DEGREE OF CHARGE-UP INDUCED BY
PLASMA USED FOR MANUFACTURING SEMICONDUCTOR DEVICE AND
APPARATUS THEREFOR

CLAIM OF PRIORITY

U.S. Patent and Trademark Office
2011 South Clark Place
Customer Window, **Mail Stop Patent Application**
Crystal Plaza Two, Lobby, Room 1B03
Arlington, VA 22202

Sir:

Applicants, in the above-identified application, hereby claim the priority date
under the International Convention of the following Korean application:

Appln. No. 1999-33858 filed August 17, 1999

as acknowledged in the Declaration of the subject application.

A certified copy of said application was submitted in the parent application.

Respectfully submitted,

VOLENTINE FRANCOS, PLLC



Kenneth D. Springer
Registration No. 39,843

12200 Sunrise Valley Drive, Suite 150
Reston, Virginia 20191
Tel. (703) 715-0870
Fax. (703) 715-0877

Dated: 30 September 2003

대한민국 특허청
KOREAN INDUSTRIAL
PROPERTY OFFICE

별첨 사본은 아래 출원의 원본과 동일함을 증명함.

This is to certify that the following application annexed hereto
is a true copy from the records of the Korean Industrial
Property Office.

출원 번호 : 1999년 특허출원 제33858호
Application Number

출원 년 월 일 : 1999년 8월 17일
Date of Application

출원 인 : 삼성전자 주식회사
Applicant(s)

1999년 11월 18일

특허청
COMMISSIONER

